

AMENDMENTS TO THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the present application.

Listing of Claims:

Claim 1 (currently amended): ~~A susceptor for s~~Semiconductor manufacturing equipment~~[[,]]~~ comprising:

a processing chamber;

a ceramic heater-block ~~[[for]]~~ installed~~ation~~ within ~~[[a]]~~ said processing chamber ~~of semiconductor manufacturing equipment;~~

an electroconductive component formed in the interior and/or on the surface of said ceramic heater-block; and

an electrode connected directly to said electroconductive component for supplying electricity thereto, said electrode having no joints or seams and being defined from where said electrode connects directly with said electroconductive component, to outside ~~[[the]]~~ said processing chamber ~~when said ceramic heater-block is installed therein.~~

Claim 2 (original): A susceptor as set forth in claim 1, further comprising a tubular piece formed encompassing said electrode.

Claim 3 (original): A susceptor as set forth in claim 2, further comprising a tubular piece formed encompassing said electrode; wherein an inert gas is introduced into the interior of said tubular piece.

Claim 4 (original): A susceptor as set forth in claim 2, wherein the space within the interior of said tubular piece is isolated from the atmosphere inside the

processing chamber when said ceramic heater-block is installed therein; and an inert gas is introduced into the interior of said tubular piece.

Claim 5 (original): Semiconductor manufacturing equipment in which is installed a susceptor as set forth in claim 1.

Claim 6 (original): Semiconductor manufacturing equipment in which is installed a susceptor as set forth in claim 2.

Claim 7 (original): Semiconductor manufacturing equipment in which is installed a susceptor as set forth in claim 3.

Claim 8 (original): Semiconductor manufacturing equipment in which is installed a susceptor as set forth in claim 4.